**INFORMATION  
DISCLOSURE  
STATEMENT**

Atty. Docket No.: 110.01420101

Serial No.: 09/691,006

Applicant(s): James R. Leger et al.

Filing Date: October 18, 2000

Group: 2877

**U.S. PATENT DOCUMENTS**

Examiner Initial	Document Number	Date	Name	Class	SubClass	Filing Date If Appropriate
100	5,042,951	08/27/91	Gold et al.			
100	5,910,841	06/08/99	Masao			
100	5,963,326	10/05/99	Masao			

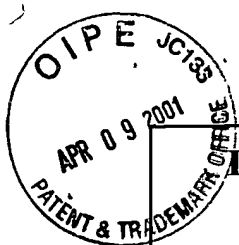
**FOREIGN PATENT DOCUMENTS**

Document Number	Date	Country	Class	SubClass	Translation	
					Yes	No
NONE						

**OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)**

100		Albersdorfer et al., "High resolution imaging microellipsometry of soft surfaces at 3 $\mu$ m lateral and 5 Å normal resolution", <u>Appl. Phys. Lett.</u> , 72(23):2930-2932 (1998).
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100		Chou et al., "Subwavelength amorphous silicon transmission gratings and applications in polarizers and waveplates", <u>Appl. Phys. Lett.</u> , 67(6):742-744 (1995).
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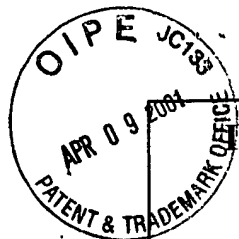
<b>EXAMINER</b> 	<b>Date Considered</b> 7/1/02
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<i>HS</i>		Spesivtsev et al., "Automatic Scanning Microellipsometer", <u>Optoelectr., Instrum. and Data Process.</u> , 1:90-94 (1997).
<i>HS</i>		Tompkins et al., "Spectroscopic Ellipsometry and Reflectometry", N.Y., John Wiley & Sons, Inc. (1999).
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<b>EXAMINER</b> <i>[Signature]</i>		<b>Date Considered</b> <i>07/1/02</i>
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